

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Takako YAMAGUCHI et al.) : Examiner: J. G. Jelsma
Application No.: 10/529,891) : Group Art Unit: 1795
Completion of Entry into U.S. National) : Confirmation No.: 7802
Stage Under 35 U.S.C. § 371(c): July 26, 2005) :
For: EXPOSURE MASK, METHOD OF DESIGNING:
AND MANUFACTURING THE SAME,)
EXPOSURE METHOD AND APPARATUS, :
PATTERN FORMING METHOD, AND DEVICE)
MANUFACTURING METHOD : December 23, 2008

Mail Stop Amendment

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

**AMENDMENT & SUBMISSION OF SUBSTITUTE SPECIFICATION
WITH PETITION FOR EXTENSION OF TIME**

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Official Action dated September 5, 2008, for one month from December 5, 2008, up to and including January 5, 2008. The statutory fee of \$130.00 for payment of the extension fee is being paid electronically. Please charge any additional fee required for the extension, or credit any overpayment, to Deposit Account 06-1205.

In response to the Official Action dated September 5, 2008, please amend the above-identified application as follows: